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PATENT
Atty. Dkt. No. AMAT/4969/CMP/ECP/RKK

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Mok, et al

Serial No.: 09/785,815

Confirmation No.: 4127

Filed: February 16, 2001

For: Integrated Semiconductor
Substrate Bevel Cleaning
Apparatus and Method

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Group Art Unit: 1763

Examiner: Sylvia MacArthur

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OFFICE OF PETITIONS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on June 25, 2003 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

6/25/03

B. Todd Patterson
Signature

STATEMENT OF COMMON OWNERSHIP

The present application (Serial No. 09/785,815; hereinafter the "Application") and Patent No. 6,516,815 (*Stevens, et al.*) were, at the time the invention of the Application was made, owned by, or subject to an obligation of assignment to, Applied Materials, Inc.

Respectfully submitted,

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